



# The grain boundary character distribution of highly twinned nanocrystalline thin film aluminum compared to bulk microcrystalline aluminum

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## ABSTRACT

The grain boundary character distribution (GBCD) of a 100-nm-thick Al thin film was measured as a function of annealing time by transmission electron microscopy-based crystal orientation mapping and compared to a bulk material with a grain size of 23  $\mu\text{m}$ . The most significant difference between the thin film and bulk GBCDs is the concentration of  $\Sigma 3$  boundaries (boundaries with a misorientation of  $60^\circ$  around  $[111]$ ), which were mostly coherent twins. The length fraction of  $\Sigma 3$  boundaries in the as-deposited thin film is 0.245, more than ten times the length fraction in the bulk sample (0.016). Although the concentrations of  $\Sigma 3$  boundaries are very different in the two samples, the population distributions are strongly correlated for all misorientations except  $\Sigma 3$ . The results indicate that the characteristic GBCD develops at grain sizes as small as 109 nm. Annealing the thin film samples at 400  $^\circ\text{C}$  for 30 min or more leads to a strong  $\langle 111 \rangle$  grain orientation texture and a decrease in the concentration of  $\Sigma 3$  grain boundaries. Grain size distributions for the samples in the current study show good agreement with prior reports that used image-based methods.

## Introduction

The properties of materials are strongly influenced by the types of grain boundaries in the material and how they are connected [1–5]. Using scanning electron

microscopy (SEM)-based electron backscatter diffraction (EBSD) [6], it has been possible to measure the relative areas of different types of grain boundaries over all five independent crystallographic parameters [7–10]. This quantity is referred to as the grain boundary

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character distribution (GBCD) and is parameterized in terms of the lattice misorientation and the grain boundary plane normal [11].

The GBCDs of many materials with grain sizes in the micrometer range have been measured using the SEM-based technique [7–10, 12–15]. The results from materials with micrometer-scale grain sizes produced by grain growth are all consistent with the conclusion that the relative populations of grain boundaries scale inversely with the grain boundary energies [16]. Studies of the same materials with different grain sizes suggest that this distribution is independent of grain size [17]. So, the question arises, at what point in microstructure development does the distribution arise? The main limitation in trying to answer this question is that the SEM-based orientation mapping does not have the spatial resolution to characterize the shapes of grain boundaries in nanocrystalline materials. With the emergence of a high-speed transmission electron microscopy (TEM) nanodiffraction-based orientation mapping technique [18–21], it has been possible to quantitatively evaluate the GBCD of nanocrystalline materials [22–28]. The ability to map orientations with a nm-scale resolution makes it possible to measure the GBCDs of nanocrystalline materials and compare them to those of microcrystalline materials. For simplicity, throughout the remainder of the text and in the title, materials with grain sizes in the micrometer range are termed microcrystalline and those with grain sizes in the nanometer range are termed nanocrystalline.

In one previous study, Liu et al. [25] measured the GBCD of a nanocrystalline tungsten film and compared it to that of a microcrystalline Fe sample, which also has body-centered cubic (BCC) structure. The correlation between the two GBCDs suggests a similarity between nanocrystalline and microcrystalline interfacial structures. Furthermore, the GBCDs of thin film nanocrystalline Cu [23, 24, 27] are consistent with bulk Cu [29]. More recently, the GBCD of an electrodeposited Cu film with micrometer-scale grains and much smaller twins was measured by EBSD and found to be similar to the GBCD of bulk Cu [30]. Here we extend the previous studies by measuring and comparing the GBCDs of thin film and bulk Al samples that have a face-centered cubic (FCC) crystal structure and grain sizes that differ by a factor of more than 200. In this case, the nanocrystalline samples are physical vapor-deposited thin films in the as-deposited state and after annealing at

400 °C. It should be noted that the structure of the thin film might impose geometric constraints on the GBCD. For example, if there is strong texture and the film is columnar, then this will constrain the types of grain boundaries that can form.

The purpose of this paper is to compare the GBCDs of an Al thin film at different stages of annealing and with grain sizes on the order of 100 nm to a bulk sample of Al with a grain size more than 200 times larger. In the results section, it is shown that the most significant difference between the GBCDs of the thin film and bulk samples is the population of  $\Sigma 3$  grain boundaries, indicating that characteristic and anisotropic GBCDs can be obtained even at grain sizes on the order of 100 nm. Annealing the as-deposited microstructure leads to grain growth, a strong  $\langle 111 \rangle$  grain orientation texture, and a decrease in the population of  $\Sigma 3$  grain boundaries.

## Materials and methods

The aluminum film examined in this work has a nominal thickness of 100 nm, similar to films we have studied previously [31]. It was sputter deposited from a 99.99% pure Al target onto an oxidized Si (100) wafer with a 300-nm-thick thermal oxide layer. The base pressure of the chamber was in the  $10^{-8}$  Torr range prior to deposition. The sputtering gas was ultrahigh purity 99.9995% Ar at a pressure of 3 mTorr and a flow rate of 20 sccm. The substrate was rotated at 10–15 rpm to ensure good thickness uniformity. The substrates were nominally at room temperature (no intentional heating). Following deposition, the substrate was cleaved into smaller pieces. These pieces were then encapsulated in borosilicate glass tubes that were evacuated to the  $10^{-6}$ – $10^{-7}$  Torr range prior to being sealed. The samples in the sealed tubes were annealed at 400°C for 30 or 150 min. This paper will compare the microstructure of the as-deposited sample with the annealed samples.

The plan-view TEM samples were prepared by first removing most of the Si substrate by mechanical polishing from the back side and then removing the rest by chemical etching using a mixture of HF and HNO<sub>3</sub> [32]. The etching was stopped in the oxide layer before breaking into the Al film, resulting in large, uniformly thick, electron transparent samples for plan-view TEM. All of the orientation maps were recorded using an ASTAR<sup>TM</sup> (NanoMEGAS, Brussels, Belgium)

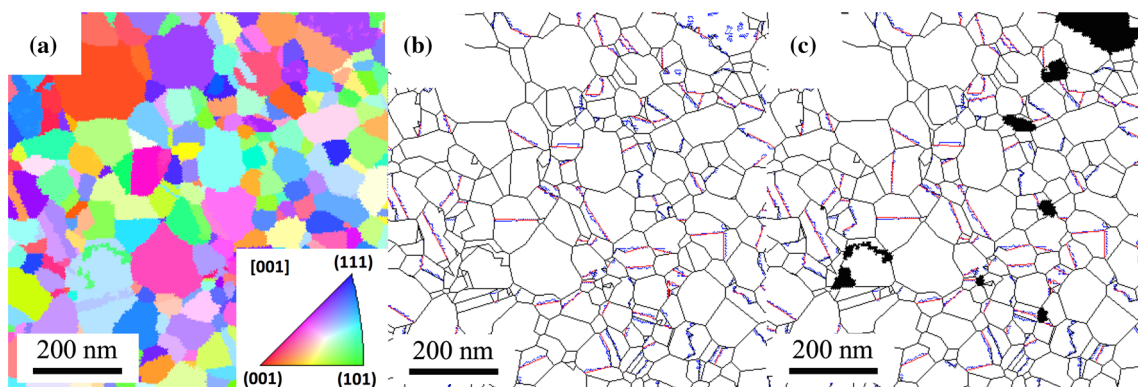
orientation mapping system installed on a Philips CM 200 TEM with a field emission gun and an accelerating voltage of 200 kV. A 20- $\mu\text{m}$  second condenser aperture was used for the mapping, and the diffraction patterns were recorded with a precession angle of  $0.6^\circ$ . Diffraction patterns, from which the orientation maps were derived, were collected at intervals (i.e., step sizes) of 4 nm for the as-deposited film and 5 nm for the two annealed films. The orientation maps were analyzed using the TSL OIM<sup>TM</sup> software (EDAX, Mahwah, NJ, USA) after adjusting for the reference frame difference between the ASTAR<sup>TM</sup> and TSL systems, as described in detail elsewhere [24].

The orientation data were subjected to a cleanup procedure to eliminate unindexed and incorrectly indexed points. First, the grain dilation filter was used with a minimum grain size of 7 pixels and a tolerance angle of  $5^\circ$ . In previous work by Liu et al. [28], the procedure for determination of the minimum grain size value in the grain dilation filter is described in more detail. Next, a single, averaged orientation was assigned to all of the pixels within a grain, assuming all adjacent pixels with disorientations  $<5^\circ$  belonged to the same grain. And finally, for the GBCD determination, grain confidence index standardization was used to assign the same confidence index to each pixel within a grain. Throughout this paper, when the term disorientation is used, it indicates the minimum misorientation.

A sample orientation map of the as-deposited Al film after cleanup is shown in Fig. 1a. In Fig. 1b, grain boundary line segments determined from the orientation maps are illustrated. Grain boundary traces were reconstructed with a grain tolerance of 2

pixels such that the line segments deviate from the true boundary positions by no more than two pixels. All boundaries within  $5^\circ$  of the  $\Sigma 3$  misorientation,  $60^\circ$  around the [111] axis, are colored blue [33]. Those  $\Sigma 3$  boundaries with line segments that are less than  $5^\circ$  from the (111) plane trace in both grains are assumed to be coherent twin boundaries and are colored red. The boundary map in Fig. 1b reveals that multiple grains have an internal, finely structured network of apparent boundaries that are likely caused by the “pseudo-symmetry” problem. These pseudo-symmetry boundaries are created within single grains where diffraction patterns can be indexed in multiple orientations related by simple symmetry operations.

For grain size determination, the pseudo-symmetry boundaries were removed using the TSL OIM<sup>TM</sup> software following the procedure detailed by Liu et al. [28], with one exception. The  $\Sigma 3$  boundaries were not removed in the current work, given that they are present in very significant fractions. The reconstructed grain boundary maps were used to obtain the grain areas using ImageJ in the manner of our previous work. [31] The edge grains were excluded from the data set. The grain areas were then used to determine three linear measures of grain size: (i) equivalent circle diameter of mean area,  $d_{\langle A \rangle} = \sqrt{\frac{4\langle A \rangle}{\pi}}$ , where  $\langle A \rangle$  is the mean value of grain areas, and (ii) and (iii) the mean and median equivalent circle diameters,  $\langle D \rangle$  and  $D_{\text{med}}$ , by first determining the equivalent circle diameter for each grain in the data set, namely  $D = \sqrt{\frac{4A}{\pi}}$ , and then determining the mean and median of these diameters. All



**Figure 1** A representative orientation map of the as-deposited Al thin film. **a** Cleaned data with grains colored by the orientation in the normal direction according to the inset key. **b** Reconstructed boundary network in which blue lines represent  $\Sigma 3$  boundaries, red

lines represent coherent twin boundaries (coherent  $\Sigma 3$  boundaries) and black lines represent all other grain boundary types. **c** Reconstructed boundary network after points with confidence index values smaller than 0.05 is removed (colored black).

three of these grain size values are given in Table 1 for the films in the current study, along with values from ref. 31 for comparison. In addition to the linear measures of grain size, grain size distributions were obtained. The reduced grain areas were determined as  $\frac{A}{\langle A \rangle}$  and then used to determine the probability density of reduced area, using a bin size of 0.1. Since in a probability density plot, the total area under the distribution is equal to one, the probability density value at each given bin takes into account the choice of bin size. The choice of 0.1 for the bin size was made to allow comparison with probability densities for Al films reported previously by Barmak et al. [31]. The probability densities for the reduced diameters,  $\frac{D}{\langle D \rangle}$ , were fitted to the lognormal distribution in a manner similar to Ref. [31].

For the determination of GBCD, while TSL OIM™ has a built-in feature which can remove all grain boundaries related by a certain user-defined misorientation relationship, it will remove both real and pseudo-symmetry boundaries, biasing the GBCD results. In this work, the pseudo-symmetry boundaries are removed via a recently reported approach [34]. Regions affected by the pseudo-symmetry boundaries usually have very small confidence index values. Therefore, by removing orientation data points with a confidence index value smaller than 0.05, most pseudo-symmetry boundaries are successfully removed, as shown in Fig. 1c.

The GBCD from the Al thin films is compared to data from a bulk Al polycrystal of commercially pure alloy 1050. This alloy is typically more than 99.5% Al;

Fe and Si are the principal impurities. The material was prepared by recrystallization and annealing at 400 °C and had an average grain size of approximately 23 μm obtained using the TSL software, and its GBCD has been reported previously; details of the preparation and features of the GBCD have already been published [15, 35]; these data are publicly available in the grain boundary data archive [36].

The GBCD,  $\lambda(\Delta g, n)$ , is defined as the distribution of relative areas of different grain boundary types distinguished by lattice misorientation, specified by the three Euler angles, and grain boundary plane orientation, specified by the two spherical angles for the direction normal to the boundary plane. The five parameter GBCD can be measured either from the stereological interpretation of EBSD data from a plane [37] or by combining EBSD with serial sectioning [7, 8, 10]. However, the GBCD of a nanocrystalline material cannot be studied by EBSD because of the limited resolution of SEM-based EBSD [38, 39]. Here, we use TEM-based orientation mapping.

The GBCD of the nanocrystalline film is determined using an established stereological interpretation of the orientation data [37]. From a crystal orientation map, four out of the five parameters used to specify a grain boundary structure are provided. The unknown parameter is the inclination angle between the surface plane and the grain boundary plane; using enough data, the distribution of inclinations can be estimated stereologically. The process assumes that the bicrystals have a random orientation

**Table 1** Al film thicknesses,  $h$ , annealing temperature,  $T$ , ratio of annealing temperature to melting point,  $T/T_m$ , annealing time,  $t$ , grain size calculated as the median of equivalent circle diameters,  $D_{med}$ , as mean of equivalent circle diameters,  $\langle D \rangle$ ,

$h$ (nm)	$T$ (°C)	$T/T_m$ (K/K)	$t$ (min)	$D_{med}$ (nm)	$\langle D \rangle$ (nm)	$d_{(A)}$ (nm)	$d_{(A)}/h$ (nm/nm)	$D_{med}/\langle D \rangle$ (nm/nm)	No. grains	Ref.
25	400	0.72	120	36	40	43	1.7	0.91	2410	31
30	450	0.77	30	116	133	149	5	0.88	8185	
100	—	—	—	75	79	85	0.9	0.95	1931	
			30	87	95	104	1.0	0.92	1324	
			60	128	145	162	1.6	0.88	1113	
			120	134	145	159	1.6	0.92	1283	
100	—	—	240	139	155	173	1.7	0.89	1516	
			600	143	159	179	1.8	0.90	759	
			—	82	93	109	1.1	0.88	13839	This study
400	0.72	30	116	131	152	1.5	0.89	13581		
		150	121	136	157	1.6	0.89	9356		

and as equivalent circle diameter of mean grain area,  $d_{(A)}$ , ratio of  $d_{(A)}$  to film thickness, median-to-mean ratio,  $D_{med}/\langle D \rangle$  and the number of grains measured for each sample



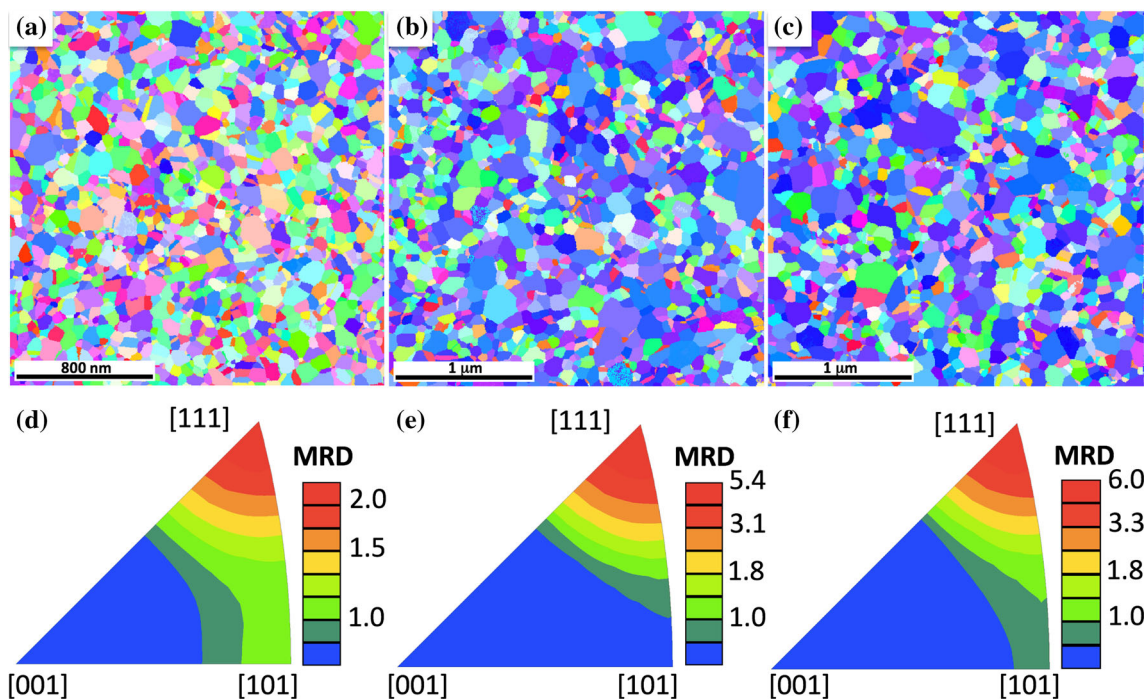
distribution. It has been shown by Saylor et al. [37] that mild orientation texture does not have a significant effect on the result. While the degree of texture that significantly affects the result has not been clearly established, simulations involving data from a cubic material that had a preferred orientation with an intensity of 2.4 multiples of random distribution (MRD) showed that this did not significantly affect the result.

Typical orientation maps of the as-deposited and annealed Al thin film samples are illustrated in Fig. 2a–c. The as-deposited thin film Al sample had inhomogeneous texture, ranging from random to a preference for having  $\langle 111 \rangle$  parallel to the sample normal (fiber texture). When the data from nine fields of view each containing more than 1500 grains with a total sampled area of approximately  $129 \mu\text{m}^2$  are combined, the  $\langle 111 \rangle$  orientation has a preferred orientation of 2.3 MRD (see Fig. 2d). This indicates only a modest degree of texture when compared to the strong  $\langle 111 \rangle$  fiber texture typically found in annealed, vacuum-deposited Al films [31]. The annealed films, on the other hand, had  $\langle 111 \rangle$  preferred orientations of 5.4 MRD (30-min annealed) and 6.0 MRD (150-min

annealed). Because of the strength of the texture in the annealed films, a stereological estimate of the grain boundary plane distribution would be biased. However, the texture in the as-deposited film is low enough to accurately compute the grain boundary plane distribution [37], which will be compared to that of the bulk sample. The GBCD of the Al film was computed from 79,000 grain boundary line segments, and the GBCD of the bulk aluminum was computed from 77,000 grain boundary line segments. A similar number of segments were used to compute the disorientation angle distributions (Fig. 6) and the misorientation axis–angle distributions (Fig. 7) for the annealed samples.

## Results

A section of the orientation map in Fig. 2a is magnified to show more details in Fig. 3a. The diffraction patterns from the grains labeled 1, 2 and 3 are shown in Fig. 3b–d, respectively. There is no evidence of overlapping diffraction patterns, indicating that the grains are continuous through the film thickness.



**Figure 2** a–c Typical orientation maps of the 100-nm Al thin films. a As-deposited, b annealed at 400 °C for 30 min and c annealed at 400 °C for 150 min. d–f Inverse pole figures for the Al film along the normal direction. d As-deposited (based on nine

maps similar to the one shown in (a)), e annealed at 400 °C for 30 min (based on eleven maps similar to the one shown in (b)), f annealed at 400 °C for 150 min (based on eight maps similar to the one shown in (c)).

Note that many of the grains are cut by long straight boundaries; these are twin boundaries, as illustrated in Fig. 1b.

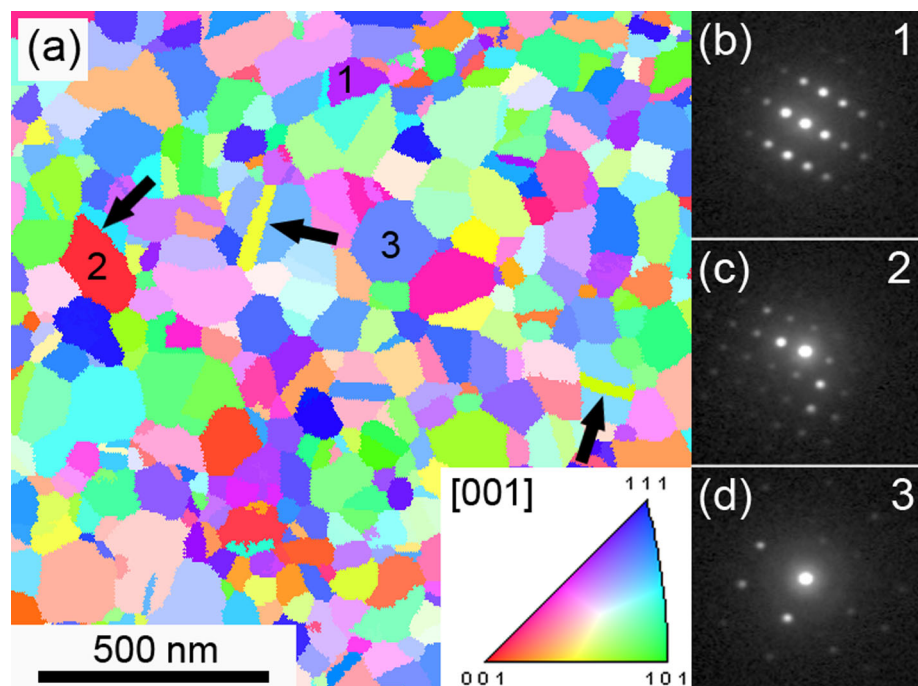
Table 1 lists the grain sizes of the films as a function of annealing time obtained from the orientation maps, along with other microstructural metrics and the numbers of grains measured for each film. Data for the Al films reported previously by Barmak et al. [31] are also given in Table 1 for comparison. The equivalent circle diameter of the mean area as a function of annealing time at 400 °C is plotted in Fig. 4. The figure shows the grain size in the as-deposited and 30-min annealed samples to be larger when compared to the study of Barmak et al. [31]. However, at 150 min, the grain size is comparable to that for 120-min annealed sample of Ref. [31]. Note that the grain size in the film annealed for 150 min (157 nm) is only 3% larger than the grain size of the sample annealed for 30 min (152 nm).

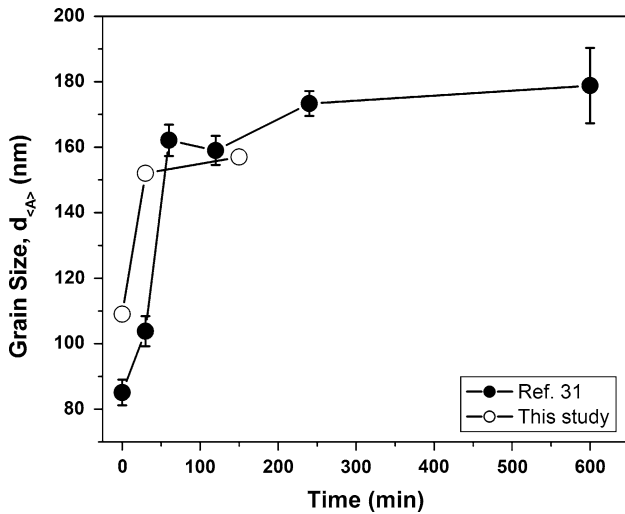
The prior study of Barmak et al. [31] showed evidence of the stagnation of grain growth as seen in Fig. 4, and thus, based on the trend in grain size as a function of annealing time, it is reasonable to conclude that the samples in the current study have also reached the stagnant stage and have done so after only 30 min of annealing. This conclusion is further supported by the close agreement of the probability

densities for reduced grain areas between the 30- and 150-min annealed samples of the current study and those for the Al films reported by Barmak et al. [31] in Fig. 5. In addition, the grain size distributions, with the measure of grain size as reduced equivalent circle diameters,  $D/\langle D \rangle$ , for the current study were found to be lognormal and in good agreement with the universal distribution reported by Barmak et al. [31] (Plots not shown). For the universal distribution, the median-to-mean grain size ratio,  $D_{\text{med}}/\langle D \rangle$ , was found to be 0.89, with the individual data sets having ratios of  $0.87 \pm 0.3$  [40]. As can be seen in Table 1, this ratio for the samples in the current study is 0.88 or 0.89, in good agreement with the prior studies summarized in [31].

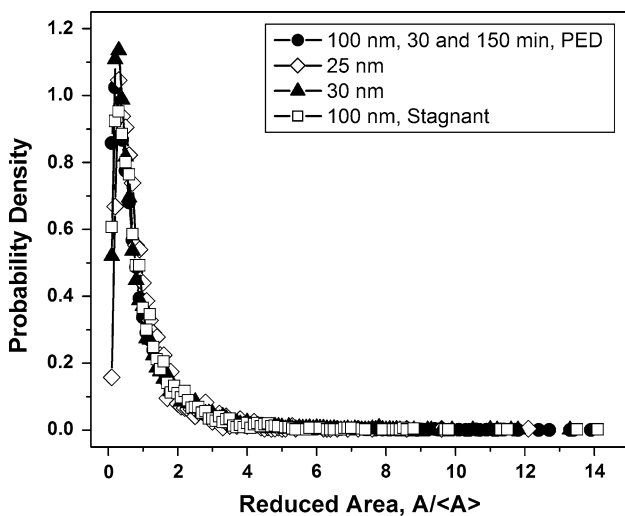
The distribution of grain boundary disorientation angles (minimum misorientation angles) for the thin film and bulk samples is compared in Fig. 6. The annealed samples have distributions that are nearly identical. The as-deposited sample is also similar, but the fraction of boundaries with 39° and 60° disorientations are greater in the as-deposited film. The bulk sample differs from the thin films in two significant ways. First, the peak at the 60° disorientation is more than seven times larger in the film than in the bulk sample. As we shall see, this peak is associated with twin boundaries. The second difference is that

**Figure 3** a Orientation map of the as-deposited Al film. Diffraction patterns in (b)–(d) correspond to the grains labeled 1, 2 and 3. The *black arrows* denote examples of long twin boundaries that cut through grains.





**Figure 4** Grain size as equivalent circle diameter of mean area,  $d_{\langle A \rangle}$ , is plotted as a function of annealing time at 400 °C for the 100-nm-thick Al films in the current study. The data for an Al film nominally 100 nm in thickness and annealed at 400 °C from Ref. [31] are given for comparison. The error bars are the  $2\sigma$  values at a 95% confidence level for the given grain population [30]. For the data set in the current work, the error bars are smaller than the size of the data points. The lines are drawn to guide the eye.



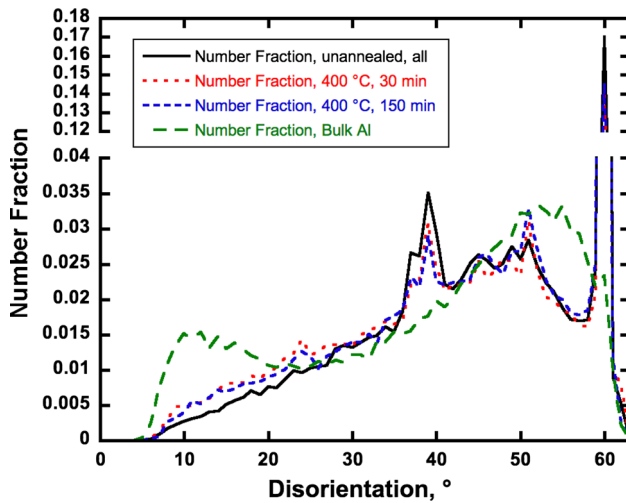
**Figure 5** Probability density of reduced grain area for the 30- and 150-min annealed Al films of the current study is compared with the densities for the Al films in the prior report of Barmak et al. [31]. A bin size of 0.1 was used for this plot. In this plot,  $A$  is the area of a given grain, and  $\langle A \rangle$  is the mean area. The reduced area,  $A/\langle A \rangle$ , is a dimensionless parameter. The data for the current study were obtained using a precession electron diffraction (PED) crystal orientation mapping-based method, whereas prior studies reported in [31] used image-based methods.

the bulk sample has an enhanced population of low-angle boundaries, compared to the thin film samples, in the range between 5° and 15°.

Sections of the grain boundary axis-angle distributions for the as-deposited film and the bulk sample are shown in Fig. 7. The sections for the annealed samples were the same as the as-deposited sample, but with small differences in the amplitudes of the maxima. For disorientations of 10°, the maximum is at [111] for both the film and bulk samples. The values of the distribution for this disorientation for all axes are greater for the bulk sample, consistent with the disorientation angle distribution (Fig. 6), which shows a local maximum at 10° for the bulk sample. At 39°, the maximum is again at [111] for the both film and bulk. However, for the film, there is also a local maximum at [101], which is the  $\Sigma 9$  grain boundary misorientation. This is consistent with the local maximum at 39° for the film in the disorientation angle distribution (Fig. 6). At the 50° misorientation, there is a significant difference between the film and the bulk; the distribution for the film maximizes at [101] with a value of 3.2 MRD (this is the  $\Sigma 11$  misorientation), and in the bulk it maximizes at [111] with a value of 2.2 MRD. The greater maximum for the film is consistent with the disorientation angle distribution in Fig. 6. In the section at 60° for the thin film (bulk), the maximum is at the [111] orientation with a value of 60 (3.6) MRD. Therefore, the majority of all grain boundaries with a 60° misorientation are  $\Sigma 3$  grain boundaries.

The grain boundary plane distribution, independent of misorientation, is illustrated in Fig. 8. For both the thin film and the bulk sample, the distributions are similar with maxima at the (111) orientation. Considering that the most common misorientation axis is [111] and the most common grain boundary plane is (111), then boundaries with (111) twist character are the most common. This is a common finding for metals with the FCC structure [29, 41]. Note that the maximum in the grain boundary plane distribution is higher for the thin film sample. This is likely the result of the higher concentration of coherent twins in the thin film sample, which is quantified below.

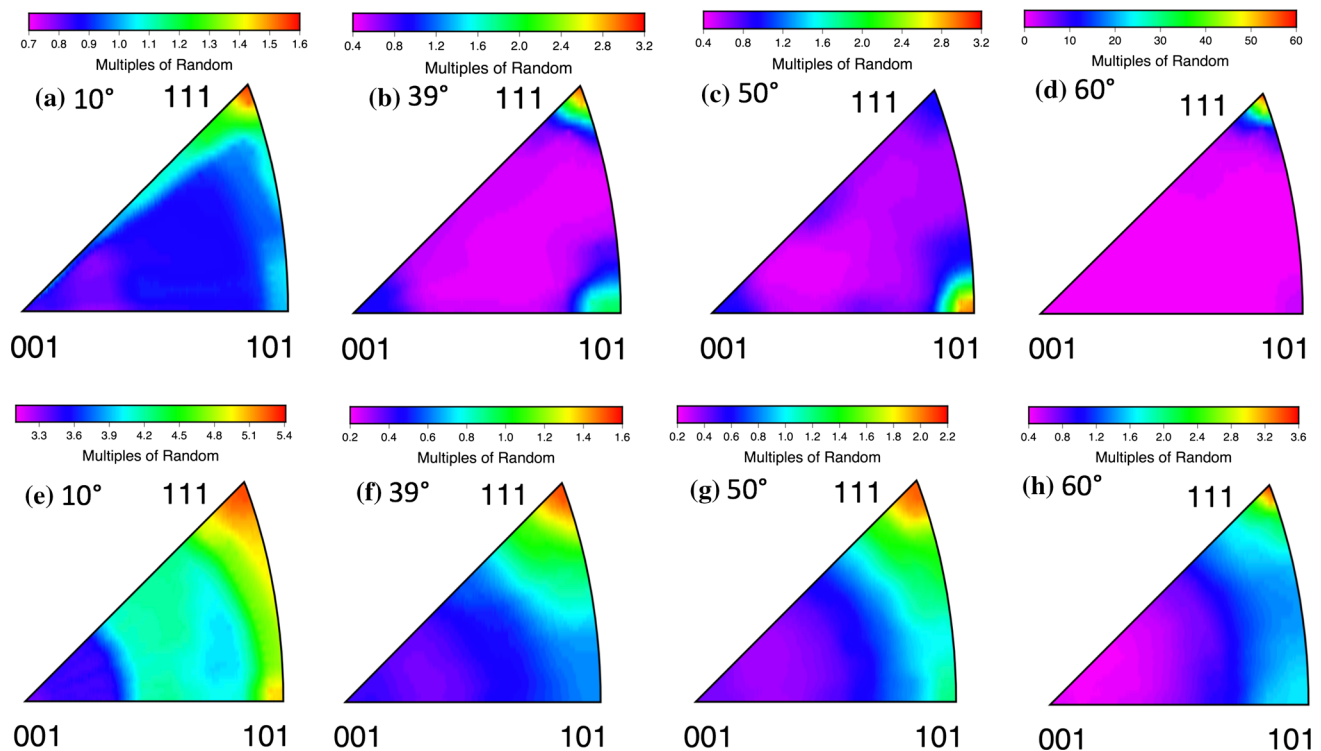
The distributions of grain boundary planes at fixed misorientations about the [111] axis ( $\Sigma 1$ ,  $\Sigma 13a$ ,  $\Sigma 7$  and  $\Sigma 3$ ) are shown in Fig. 9. The maximum for each distribution is at the (111) position; because the grain boundary planes are perpendicular to the [111] misorientation axes, these are all twist boundaries.



**Figure 6** Disorientation angle distributions for the different samples. The disorientation values are classified discretely in bins with a  $1^\circ$  width. As-deposited thin film (unannealed): *solid black line*. Thin film annealed for 30 min at  $400^\circ\text{C}$ : *red dashed line with the shortest dashes*. Thin film annealed for 150 min at  $400^\circ\text{C}$ : *blue dashed line with intermediate length dashes*. Bulk aluminum: *green dashed line with the longest dashes*.

These results are consistent with Fig. 8, which shows that  $\{111\}$  is the most common grain boundary plane orientation when all misorientations are considered. For the case of the  $\Sigma 3$  boundary, this shows that they are mostly coherent twins. Note that the maximum at the coherent twin position for the thin film sample is 700 MRD, more than 20 times the maximum in the bulk sample (30 MRD). The distribution of grain boundary planes for the bulk sample at  $5^\circ$  about  $[111]$  has secondary maxima at  $\{111\}$  positions that are not observed in the thin film sample. With the exception of the aforementioned secondary maxima and the large intensity difference at the coherent twin position, the distributions in the bulk and thin film are similar.

Two examples of the grain boundary plane distribution at other misorientations are shown in Fig. 10. The  $\Sigma 19a$  misorientation is an example of a boundary that occurs infrequently; the maxima in the distribution for the as-deposited film do not exceed 2.2 MRD. Although not exactly the same, the grain

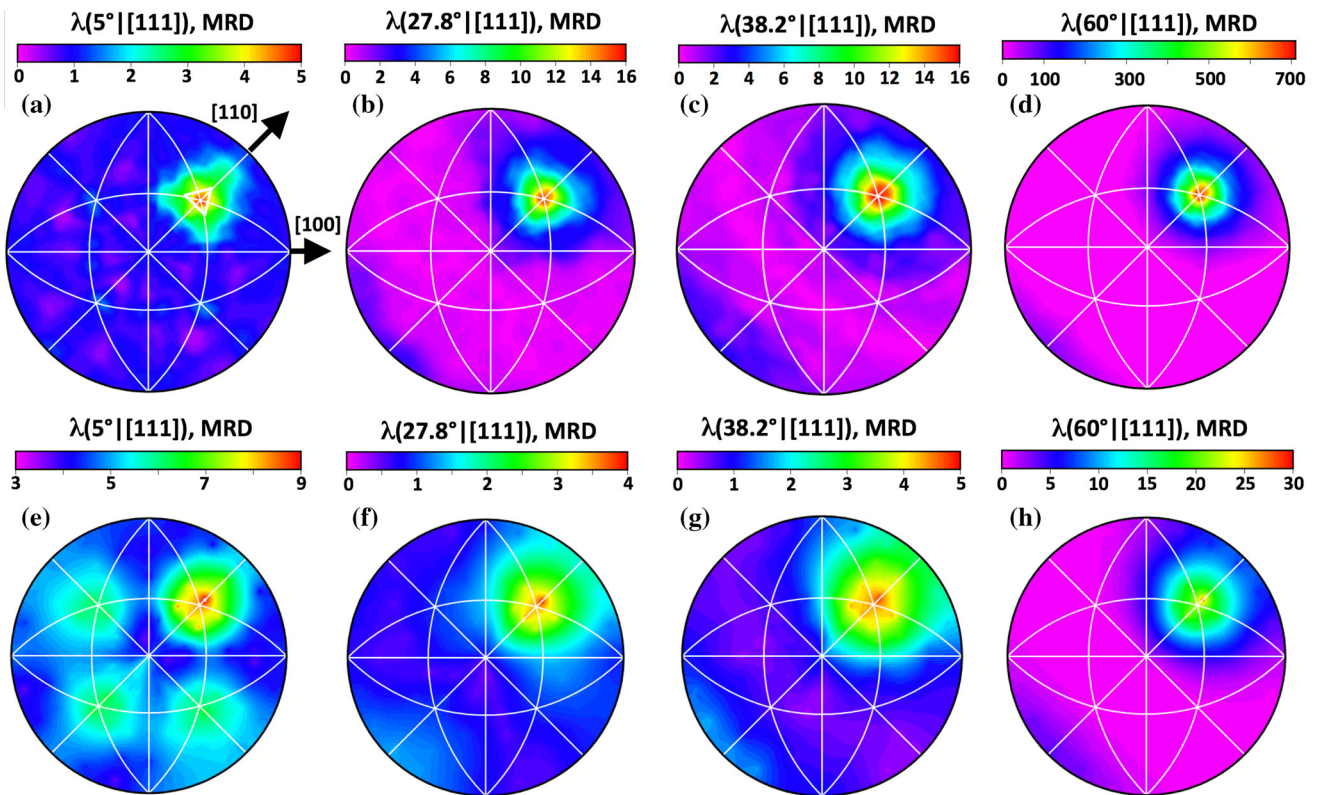
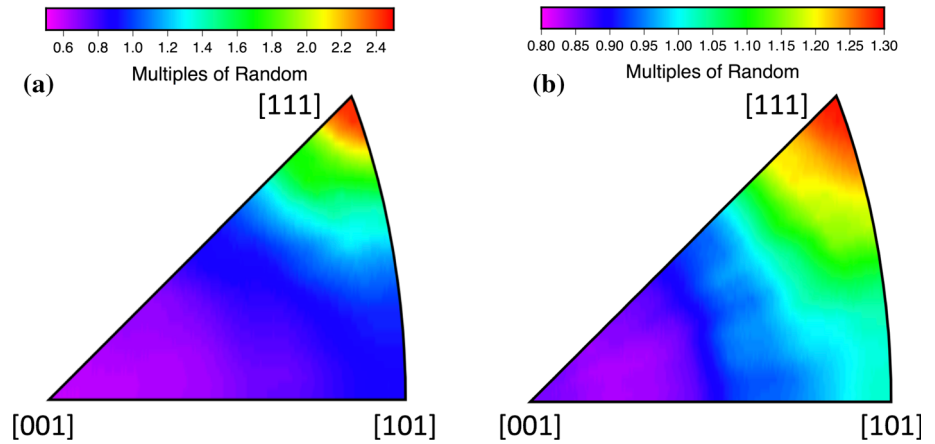


**Figure 7** Distributions of grain boundaries in axis-angle space for the as-deposited thin film (a–d) and bulk (e–h) samples. In each section, all possible axes are shown and the population is

plotted at  $10^\circ$  (a, e),  $39^\circ$  (b, f),  $50^\circ$  (c, g) and  $60^\circ$  (d, h). The distributions are discrete and calculated with a resolution of  $7.5^\circ$ .



**Figure 8** Distribution of grain boundary planes independent of misorientation for the as-deposited thin film (a) and bulk (b) samples. The distribution is discrete and was calculated with a resolution of 7.5°.

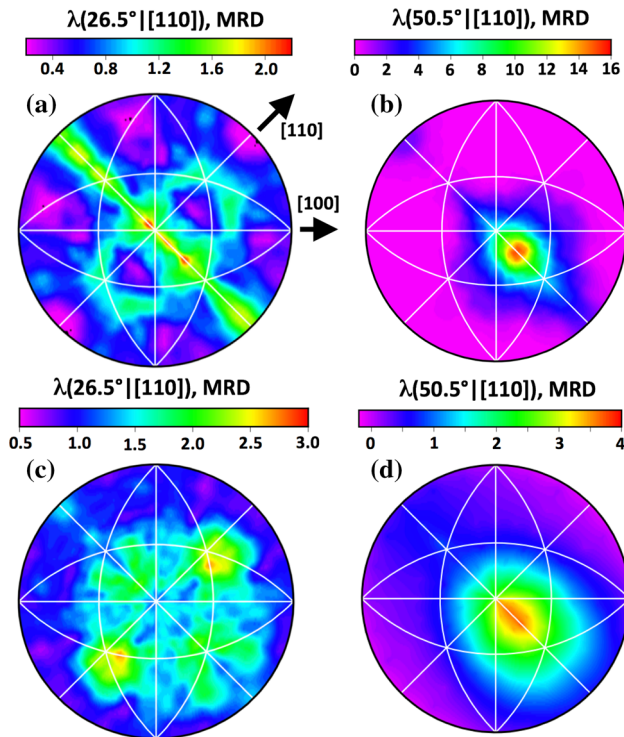


**Figure 9** Distribution of grain boundary planes at fixed misorientations for the as-deposited thin film (a–d) and bulk (e–h) samples. The misorientations are  $\Sigma 1$  (a, e),  $\Sigma 13a$  (b, f),  $\Sigma 7$  (c, g) and  $\Sigma 3$  (d, h). The [110] and [100] directions are in the plane

and marked with *black arrows* in (a). The [111] direction is marked by a *white triangle*. The same convention is used in all of the grain boundary plane distributions.

boundary plane distributions for the  $\Sigma 19a$  misorientation are similar. For the thin film, the maxima occur for planes that are perpendicular to the misorientation axis, in the [110] zone. There are weaker local maxima at several other orientations, including (111) and  $(\bar{1}\bar{1}0)$ . For the bulk sample, on the other hand, the maxima are at these positions [(111) and  $(\bar{1}\bar{1}1)$ ] and

there are weaker local maxima along the [110] zone. These differences, of no more than 1 MRD, are not thought to be significant. The distributions of grain boundary planes are also similar for the  $\Sigma 11$  grain boundary, where the maximum in the distributions of the bulk and film samples are at the position of the  $(1\bar{1}3)$  symmetric tilt boundary.



**Figure 10** Distribution of grain boundary planes at fixed misorientations for the as-deposited thin film (a, b) and bulk (c, d) samples. The misorientations are  $\Sigma 19a$  (a, c) and  $\Sigma 11a$  (b, d). The [110] and [100] directions are in the plane and marked with black arrows in (a).

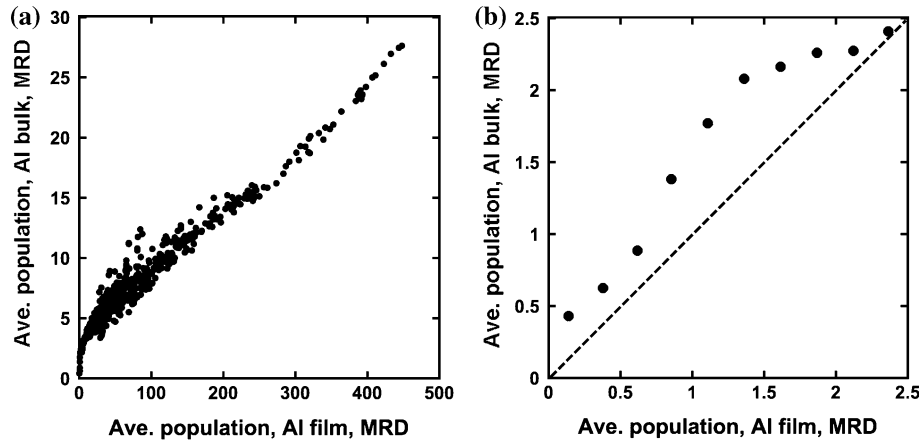
To make a more quantitative comparison between the distributions, we average the populations of all grain boundaries that have a population that is within an interval of 0.25 MRD in the Al thin film. We then average the populations of the boundaries with the same crystallographic parameters in the bulk Al. When this is repeated for all possible intervals and these two averages are plotted on a graph, the result is shown in Fig. 11a. The strong linear characteristic of the graph illustrates that if a boundary is highly populated in the nanocrystalline sample, it is also highly populated in the microcrystalline sample. However, Fig. 11a is biased to show the population of  $\Sigma 3$  boundaries, which in the film are all boundaries with populations greater than 30 MRD. In this domain, the slope is much less than unity. However, if one examines the correlations among the non- $\Sigma 3$  boundaries (see Fig. 9b), the data are correlated with a slope more nearly equal to one. The positive deviation from the ideal correlation in Fig. 11b is the result of the difference in the concentration of  $\Sigma 3$  boundaries in the two samples; the relative areas of

the non- $\Sigma 3$  boundaries are higher in the bulk sample, because a smaller fraction of the total area is made up of  $\Sigma 3$  boundaries. The comparison in Fig. 11 shows that the similarity of the distributions illustrated in Figs. 9 and 10 is representative of the entire data set. Specifically, the grain boundary character distributions in thin film nanocrystalline Al and bulk microcrystalline Al are similar, except that there are many more twins in the thin film.

## Discussion

With the exception of the high concentration of twins in the thin film samples, the populations of grain boundaries in the nanocrystalline sample and the microcrystalline sample are similar. The GBCD is dominated by misorientations about the [111] axis and of these boundaries, twist boundaries are the most common. It has been shown that the populations of grain boundaries in Al are inversely correlated to the calculated grain boundary energies [35]. The present work indicates that this distribution can be achieved at the very earliest stages of grain growth, when the average grain size is approximately 100 nm. The distribution is thought to develop by the elimination of relatively higher energy grain boundaries in favor of relatively lower energy grain boundaries [42]. A simulation of this process indicated that the size invariant distribution develops during a doubling of the grain size by normal grain growth [43]. It has also been observed in simulations and experiments that, after extensive grain growth, the fraction of low disorientation angle grain boundaries (which have relatively low energies) exceeds that expected in a random distribution [44]. This is a plausible reason for the elevated population of low-angle grain boundaries in the bulk sample.

The high concentration of twins in the nanocrystalline Al sample must be noted as both unusual and surprising. While twins are common in other FCC metals with lower stacking fault energies, their populations are not as large in Al. The stacking fault energy in Al has been calculated to be 66–280 mJ/m<sup>2</sup> [45–48]. For comparison, the stacking fault energy of Cu and Ag, which has highly twinned microstructures, calculated via different approaches is 14–78 and 1–22 mJ/m<sup>2</sup>, respectively [49–51]. While Al can twin by deformation [52–54], these films were heated to 400 °C, well above the temperature at which



**Figure 11 a–b** Correlation of the populations of the same boundaries in the as-deposited film and bulk Al. The average of all grain boundaries in the thin film with populations in an interval of 0.25 MRD is found, and the populations of the same boundaries

in bulk Al are averaged. Each point on the plot represents the two averages in a single population interval. In (b), the *dashed line* has a slope of one and represents the ideal correlation and is added as a guide to the eye.

stresses in Al are relaxed [55]. This, and the fact that twins are seen in the as-deposited (unannealed) film, suggests that the twins were not mechanically introduced during annealing.

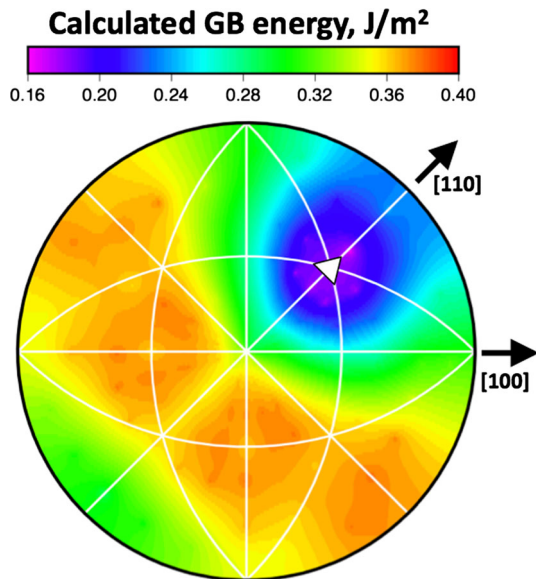
Other materials that have significant numbers of  $\Sigma 3$  boundaries are Si [13] and Cu [30]. In these cases, it has been noted the high concentration of  $\Sigma 3$  boundaries leads to an elevated concentration of  $\Sigma 9$  boundaries. When two  $\Sigma 3$  grain boundaries meet, a  $\Sigma 9$  boundary is formed [56]. If distributed randomly, one would expect the number fraction of  $\Sigma 3$  grain boundaries squared (the probability that they intersect) would equal the concentration of  $\Sigma 9$  boundaries. This is approximately correct for Si [13] and Cu [30]. Here, however, there are fewer  $\Sigma 9$  grain boundaries than would be expected based on this line of reasoning. In the as-deposited sample, 20% of all boundaries are  $\Sigma 3$  type, suggesting that 4% of the boundaries should be  $\Sigma 9$ . In fact, only 2.7% are  $\Sigma 9$ . In the sample annealed for 30 (150) minutes, the  $\Sigma 3$  concentration is 17 (18) % and the  $\Sigma 9$  concentration is 1.9 (1.7) %. The lower concentration of  $\Sigma 9$  boundaries suggests that the  $\Sigma 3$  boundaries are not randomly distributed, and this might be connected to their mechanism of formation during the growth process.

There are interesting changes in the microstructure during annealing. In the first 30 min of annealing, the average grain diameter increases from 109 to 152 nm, implying that (assuming a columnar, 2D grain structure) half of the grains and grain boundaries are eliminated by grain growth. The  $\langle 111 \rangle$  grain

orientation texture also strengthens considerably, from about 2 MRD to about 6 MRD.

Grain growth in thin films can be affected by driving forces other than grain boundary energy reduction. Two of the most important of these driving forces are surface and elastic-strain energies. [57] The reduction in these energies results in the growth of a subpopulation of grains and leads to the development of film texture. The calculated texture map for Al films [40] shows that for the film thickness, and deposition and annealing temperature used in the current study, surface energy reduction dominates and thus the  $\langle 111 \rangle$  fiber texture of the film is strengthened as grain growth proceeds.

At the same time, the concentration of  $\Sigma 3$  boundaries decreases. The length fraction of  $\Sigma 3$  boundaries decreases from 24.5% in the as-deposited sample to 18.8% (21.1%) in the sample annealed for 30 (150) minutes at 400 °C. Because the  $\Sigma 3$  boundaries are among the lowest energy boundaries, it is unusual that their concentration decreases during growth. However, this might be related to the sample geometry and the elimination of excess grain boundary energy during grain growth. Note that the grain boundary area (and energy) is minimized when the boundaries are perpendicular to the free surface of the sample. However, because the preferred grain orientation is  $\langle 111 \rangle$ , a twin grain boundary is geometrically constrained to be inclined with respect the surface normal, having an area that is 15% greater than a boundary that is perpendicular surface. The



**Figure 12** Energies of the  $\Sigma 3$  grain boundaries in Al calculated by Olmsted et al. [58]. The misorientation axis is marked by a triangle. The energies reach a maximum along the [111] zone, which are the positions of the [111] tilt boundaries.

range of energies of  $\Sigma 3$  grain boundaries is illustrated in Fig. 12. This is similar to the range of energy of other types of grain boundaries in Al [58]. Therefore, it is possible that a boundary that is normal to the sample surface, with a higher energy per unit area, could be favored over a grain boundary with a lower energy per unit area, but that is constrained to be inclined and thus have a higher total energy in the film. Therefore, the combination of film texture and geometry might disfavor low-energy boundaries that are constrained to be inclined with respect to the sample surface. The grain boundary energy distribution in Fig. 12 also indicates that tilt grain boundaries between two [111] oriented grains (those favored by the geometry of the [111] textured film) have a relatively high energy, at least for  $\Sigma 3$  boundaries. In Fig. 12, the tilt boundaries are those perpendicular to the [111] direction.

The question arises as to how such a high concentration of  $\Sigma 3$  grain boundaries forms in the Al film, while boundaries of the same crystallography occur much less frequently in bulk Al. This is currently not known but might be related to the evolution of film structure during deposition [57]. Al films, vapor deposited on amorphous substrates such as oxidized silicon wafers, as in the current study, form

by nucleation, growth and coalescence of metal islands. When an island pair comes into touching contact, the free surfaces snap together and form a grain boundary in place of the two free surfaces [59]. The grain boundary energy is much less than the energy of the two free surfaces, with {111} boundary planes for both grains providing the lowest boundary energy among all possible boundaries. The {111} boundary continues to lengthen as the film thickens, but once the film is fully coalesced, the reduction in surface, strain and grain boundary energies will drive grain growth and reduce the overall {111} boundary area, as noted earlier. If this is the mechanism for formation of twin boundaries in thin films, then it is unclear whether it is possible to replicate such a high  $\Sigma 3$  concentration in a bulk material.

## Conclusions

The grain boundary populations in nanocrystalline Al and microcrystalline Al are correlated. The populations are quite similar, except for the unusually high population of twins in the thin film sample (24.5% by length). Assuming the grain boundary character distribution is determined by the energy anisotropy, and these findings indicate the steady-state distribution (for all but the  $\Sigma 3$  misorientation) can be reached at grain sizes as small as approximately 100 nm. When the grains grow after deposition, the reduction in surface and interface energy drives the growth of  $\langle 111 \rangle$  grain orientations and strengthening of the  $\langle 111 \rangle$  fiber texture. The geometric constraints imposed by the texture and form factor of the film likely contribute to a reduction in the fraction of  $\Sigma 3$  misorientations during post-deposition grain growth.

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## Compliance with ethical standards

**Conflicts of interest** No conflicts of interest exist for any of the authors.

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